4π Silicon Hybrid Detector with Charged Particle Identification and Highest Position Resolution for an Experiment at EIC

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SILICON PIXEL-BASED PARTICLE VERTEX AND TRACKING DETECTORS TOWARDS THE US ELECTRON ION COLLIDER WORKSHOP, September 02-04, 2020





a passion for discovery





Project Member: International Collaboration

Project members have extensive record on the construction of silicon detectors:

- Silicon strip
 - detector
- Silicon pixel
- detector
- Silicon hybrid pixel
- SOIMPXD
- UFSD: LGAD,

AC-LAGD

- Silicon readout
- 0.000
- Silicon assembly
- Cooling system
- Integration
- Commissioning
- And more

Project Members:

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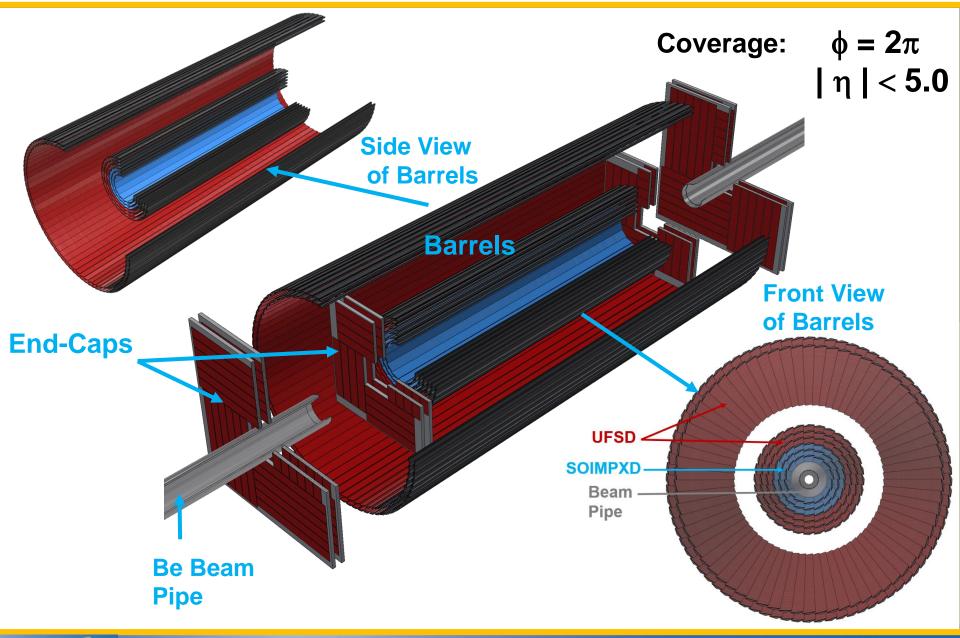


We welcome people/institutions to join the project



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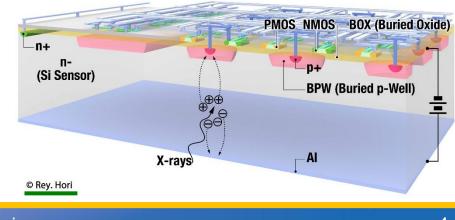
4π Silicon Hybrid Detector = SOIMPXD + UFSD





Why Silicon-On-Insulator Monolithic PiXel Detector (SOIMPXD)?

- Monolithic device. No mechanical bonding.
- Fabricated with semiconductor process only \rightarrow High reliability and Low Cost.
- High Resistive fully depleted sensor (50 um~700 um thick) with Low sense node capacitance → Large S/N.
- On Pixel processing with CMOS circuits.
- No Latch up and very low Single Event cross section.
- Can be operated in wide temperature (1K-570K) range.
- Based on Industry Standard Technology

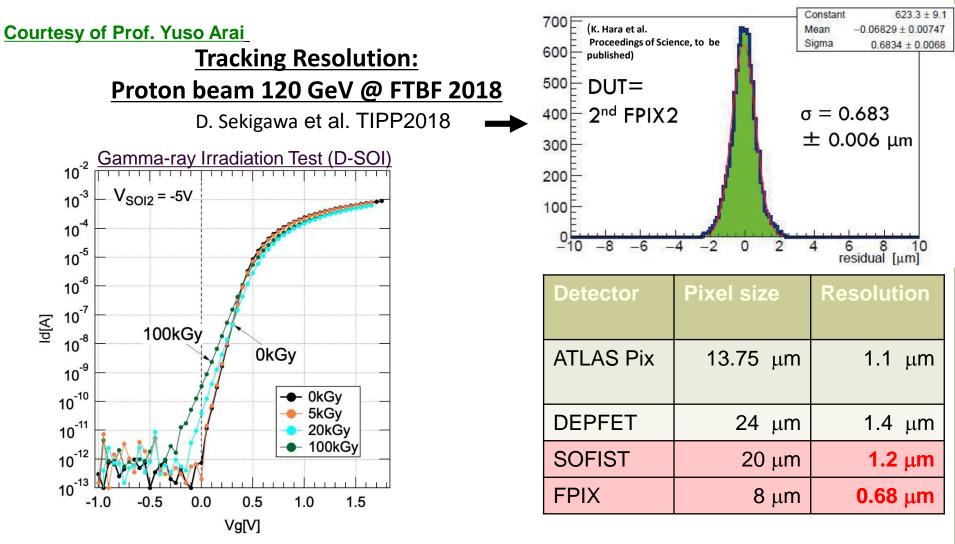




Why Silicon-On-Insulator Monolithic PiXel Detector (SOIMPXD)?

SOIMPXD has the best tracking position resolution in the world 0.68 μ m, high radiation

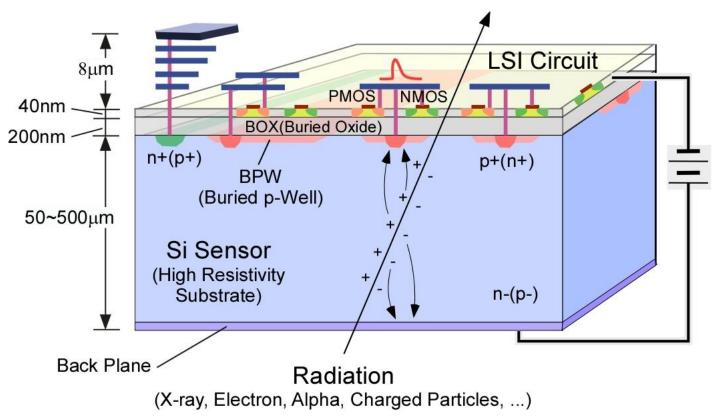
tolerance more than 10 Mrad (Si), time resolution ~ 1μ s, and low material budget.





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Courtesy of Prof. Yuso Arai

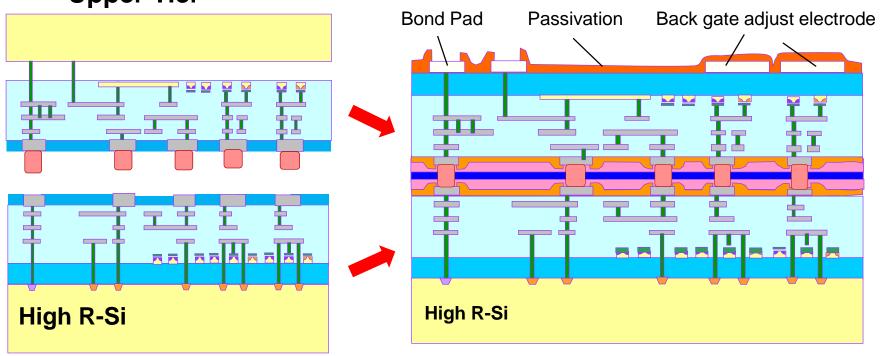


Monolithic Detector having fine resolution of silicon process and high functionality of CMOS LSI by using a SOI Pixel Technology.

3D Vertical Integration

Upper Tier

SOFIST Ver. 4



Lower Tier

Upper and Lower Tier chips are produced in a same wafer and bonded chip to chip.

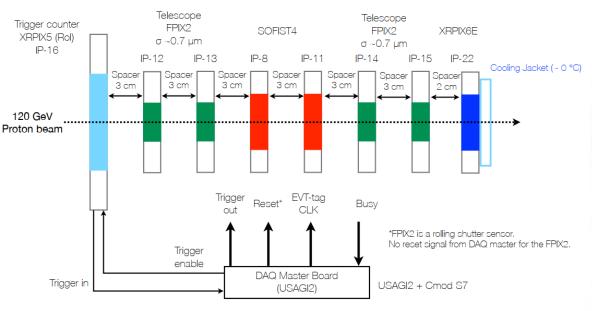


Extensive Program Achieved on SOIMPXD using Beam Test at FNAL

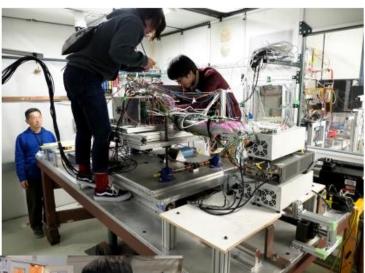
	SOFIST1	SOFIST2	SORST3	SOFIST4 (3D)
Courtesy of Mil	Beam test at FNAL in Jan. 2017 Analog signal ho Yamada	Beam test at FNAL in Feb. 2018 Analog signal or Timestamp	Beam test at FNAL in Feb. 2019 Analog signal and Timestamp	Beam test at FNAL in Feb. 2020 Analog signal
Chip Size (mm²)	2.9 × 2.9	4.45 × 4.45	6×6	4.45 × 4.45
Pixel Size (µ m²)	20 × 20	25 × 25	30 × 30	20 × 20
Pixel Array	50 × 50 (Analog Signal)	64 × 64 (Time Stamp) 16 × 64 (Analog Signal)	128 × 128 (Analog signal and Time stamp)	104 × 104 (Analog signal and Time stamp)
Functions (Pixel)	Pre. Amplifier (CSA) Analog signal memory (2 hits)	Pre. Amplifier (CSA) Comparator (Chopper inverter) Shift register (DFF × 2) Analog signal memory (2 hits) or Time stamp memory (2 hits)	Pre. Amplifier (CSA) Comparator (Chopper inverter) Shift register (DFF × 3) Analog signal memory (3 hits) Time stamp memory (3 hits)	Pre. Amplifier (CSA) Comparator (Chopper inverter) Shift register (DFF × 3) Analog signal memory (3 hits) Time stamp memory (3 hits)
Functions (On Chip)	Column ADC (8 bit)	Column ADC (8 bit) Zero-suppression logic	Column ADC (8 bit)	Column ADC (8 bit)
Wafer	FZ n-type (Single SOI)	Cz p -type (Double SOI)	FZ p -type (Double SOI)	FZ p -type (Double SOI)
Wafer Resistivity (kQ-cm)	2≤	1≤	3 - 10	3 - 10
Status	Delivered (Dec. 2015) Position resolution ~1.4 µm	Delivered (Jan. 2017) Time resolution ~1.55 µs	Delivered (May. 2018) Under evaluation	Delivered (Jan. 2019 ~)



SOIMPXD @ FBTF Feb. 26th - Mar 8th, 2020: 120 GeV Proton Beam



Courtesy of Miho Yamada



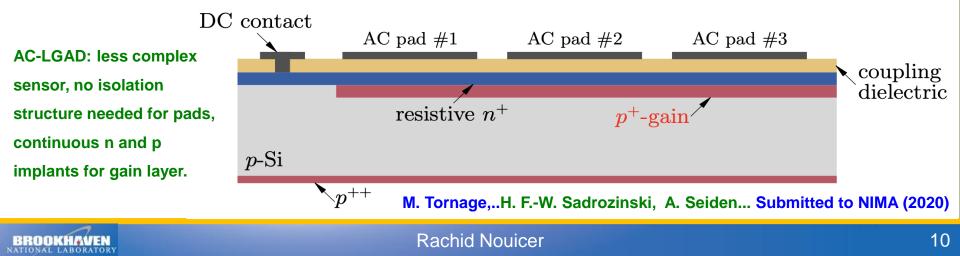




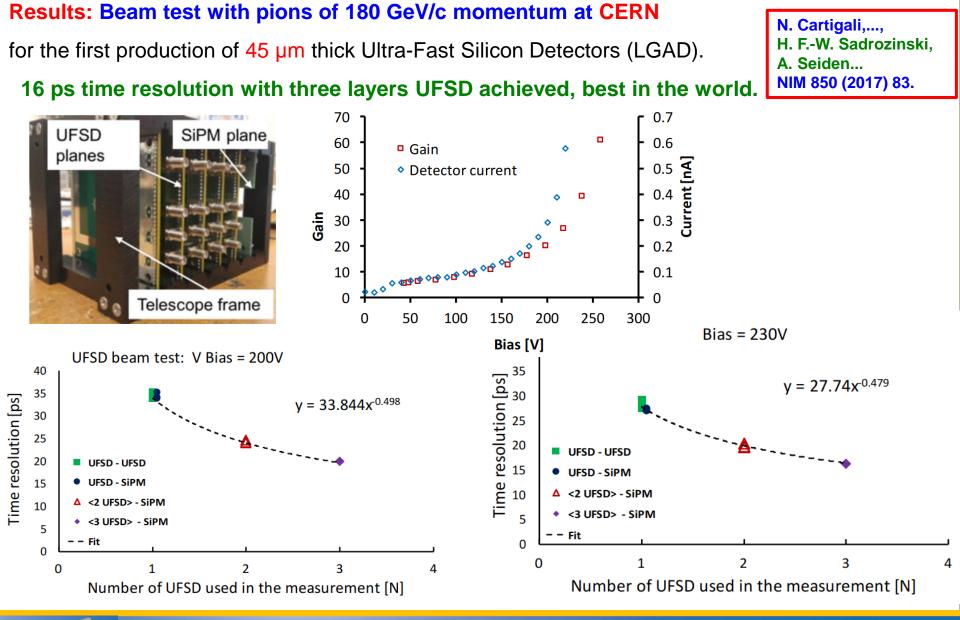




- Ultra Fast Silicon Detector (UFSD) are thin pixelated silicon sensors based on the Low Gain Avalanche Detector (LGAD) design which uses one extra implant during the sensor fabrication to achieve an intense electric field in a few micron region near the detector junction. The large electric field is able to start an avalanche multiplication for the collected electrons. The resulting large and fast signal allows the measurement of the particle hit time determination to be improved from nanoseconds to picoseconds. Developed by CNM Barcelona (Spain) first, HPK Hamamatsu (Japan), FBK Trento (Italy), and BNL (US).
- Can deliver the timing accuracy needed for ToF/PID and physics at the EIC
- > Can be arranged in an array covering large areas as conventional silicon detectors for tracking
- The AC-LGADs are actually fairly simple compared to for example strip detectors (no large number of individual strips with polysilicon resistors) and not exceptionally difficult to fabricate, BNL was able to make them. Should result in reduced cost.



UFSD: Beam Test at CERN



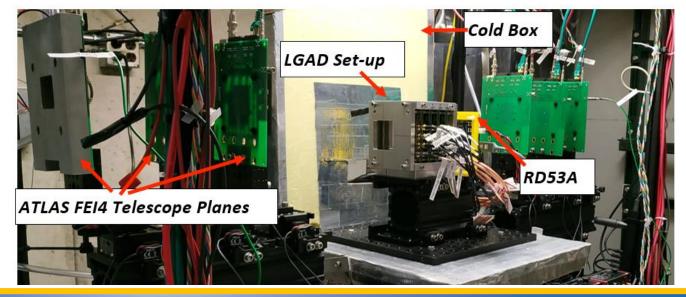


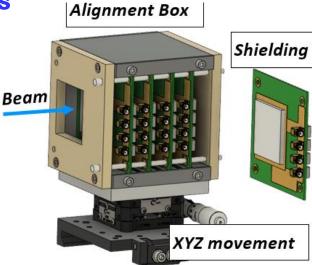
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UFSD: Beam Test at Fermi Lab 2019

Achieved by ANL (Argonne) and UC (Santa Cruz) groups

- Proton Beam with momentum 120 GeV
- Objective of evaluation of time resolution for minimum ionising particles and effect of more than one sensor plane
- Four LGAD sensors placed in alignment box mounted on XYZ stage
- Sensors HPK 1.2 (35μm), 3.1(50μm) were tested
- Cold temperature measurements at -30 °C is achieved using FP89-ME Julabo Chiller
- Data were collected in spills of 4 sec duration and instantaneous trigger rate between 1 and 5 Hz were achieved





Courtesy of Manoj Jadhav



UFSD: Beam Test at Fermi Lab 2019

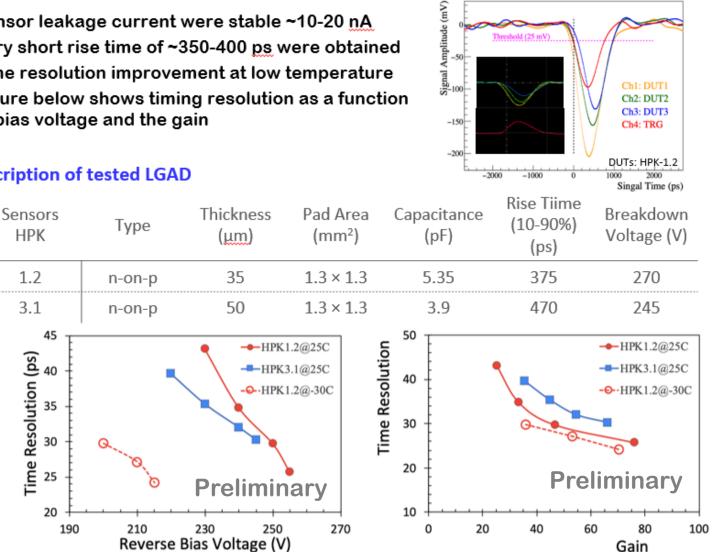
Achieved by ANL (Argonne) and UC (Santa Cruz) groups

Courtesy of Manoj Jadhav

Threshold (25 mV

Timing Resolution

- Sensor leakage current were stable ~10-20 nA
- Very short rise time of ~350-400 ps were obtained ٠
- Time resolution improvement at low temperature ٠
- Figure below shows timing resolution as a function of bias voltage and the gain



Description of tested LGAD



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UFSD: Beam Test at Fermi Lab 2019

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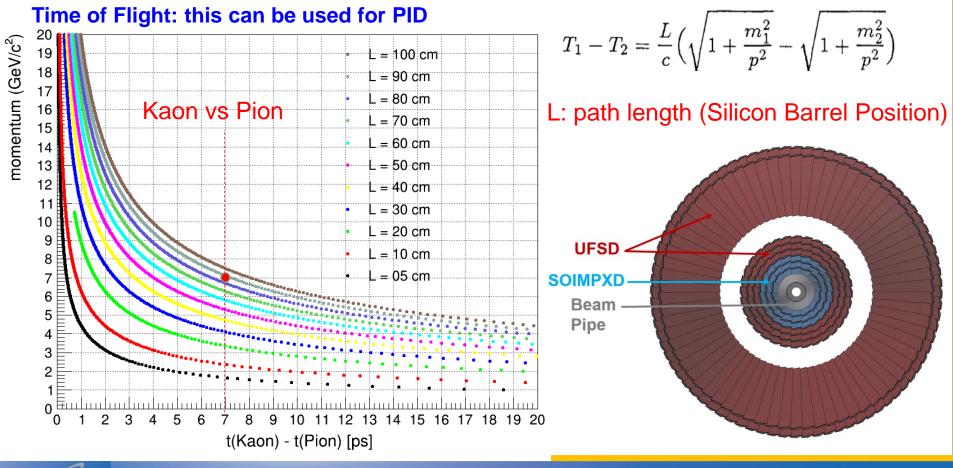
Courtesy of Manoj Jadhav

Timing Resolution: to be submitted for publication soon Normalised Entries Landau MPV Landau Width Gaussian Mear Gaussian Sig Achieved timing resolution of about 14.73 ps 0.22 145.66 ± 0.53 10.56 ± 0.22 159.35 ± 0.49 25.91 ± 0.39 116.53 ± 0.70 10.11 ± 0.31 129.07 ± 0.64 24.70 ± 0.55 0.2 Normalized signal amplitude vs. Bias Voltage ٠ 85.22 ± 0.44 8.94 ± 0.20 97.54 ± 0.51 22.20 ± 0.42 0.18 54.79 ± 0.59 7.93 ± 0.34 75.00 ± 0.67 18.09 ± 0.53 Time Resolution vs. No. Of UFSDs 0.16 0.14 UFSD HPK-1.2 V_{bine} = 255 V; Gain ~ 76 0.12 $V_{\text{bias}} = 240V$ Vbias = 255V $V_{\text{bias}} = 215V$... = 250 V; Gain ~ 46 **HPK1.2** 0.1 V_{bine} = 240 V; Gain ~ 33 (25 °C) (25 °C) (-30 °C) V_{bine} = 230 V; Gain ~ 25 0.08 **Preliminary** 0.06 N = 134.78 ps 25.7 ps 24.17 ps 0.04 24.77 ps 18.79 ps N = 218.11 ps 0.02 0 50 100 150 200 250 300 350 400 15.04 ps 14.73 ps N = 3Signal Amplitude (mV) 40 40 UFSD beam test: Operating Temperature = 25 °C UFSD beam test: Operating Temperate 35 35 34.949x^{-0.48} HPK-1.2 (35 μm) $v = 29.382x^{-0}$ HPK-1.2 (35 μm) Time Resolution (ps) Fime Resolution (ps) 30 30 29.856x^{-0.490} = 26.281x^{0.48} 25.794x^{-0.473} 25 25 = 24.263x^{-0.437} 20 20 DUT-DUT: 255V OUT-DUT: 215V 15 O DUT-TRG: 255V 15 O DUT-TRG: 215V DUT-DUT: 250V DUT-DUT: 210V 10 10 **Preliminary** DUT-TRG: 250V **Preliminary** DUT-TRG: 210V DUT-DUT: 240V 5 5 DUT-DUT: 200V DUT-TRG: 240V DUT-TRG: 200V ٥ 0 Number of UFSDs (N), <N-UFSD> Number of UFSDs (N), <N-UFSD>



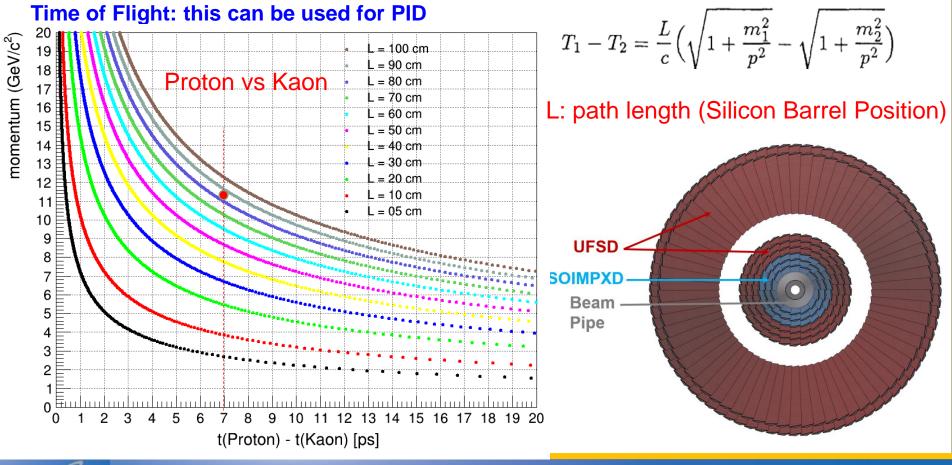
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- > 3 layers UFSD (35 μ m) → 15 ps time resolution (measured)
- > Goal: UFSD (AC-LGAD) with 20 μ m thickness of sensor \rightarrow 5 to 10 ps time resolution
- Basic Math: Two particles with the same momentum but different masses have different



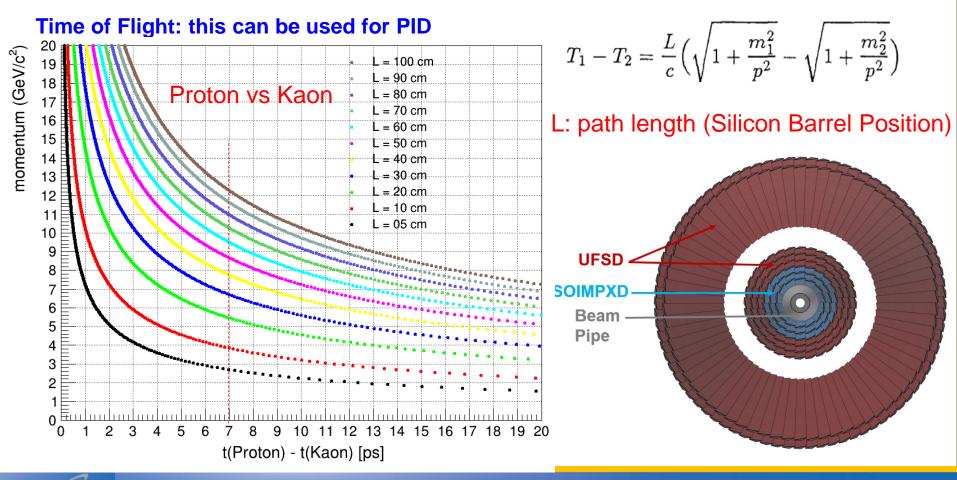
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Simulation is needed to confirm PID with UFSD



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Summary

- Silicon-On-Insulator Monolithic PiXel
- **Detector (SOIMPXD) and Ultra-Fast Silicon**
- Detector (UFSD) provide best of silicon detector
- technology for tracking and particle
- identification:
- SOIMPXD: best position resolution < 1 μ m
- UFSD: best timing resolution < 16 ps (5 to 10 ps)
 - SOIMPXD + UFSD = Silicon Hybrid Detector is state-of-art of silicon detector technology which EIC can use to search for new physics discoveries.

